

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Yasuo KOBAYASHI, et al. Confirmation No.: 7185
U.S. Serial No. : 10/549,859
Filed : June 6, 2006
Examiner : Michael G. Miller
Group Art Unit : 1792
For : PLASMA-ASSISTED DEPOSITION METHOD AND PLASMA-
ASSISTED DEPOSITION SYSTEM

AFTER FINAL AMENDMENT RESPONSE UNDER 37 CFR 1.116

Mail Stop: AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This is in response to the Final Office Action of November 1, 2010, to which the time for response is set to expire February 1, 2011, please amend the application as set forth below and consider the following remarks.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.